# This Page Is Inserted by IFW Operations and is not a part of the Official Record

## **BEST AVAILABLE IMAGES**

Defective images within this document are accurate representations of the original documents submitted by the applicant.

Defects in the images may include (but are not limited to):

- BLACK BORDERS
- TEXT CUT OFF AT TOP, BOTTOM OR SIDES
- FADED TEXT
- ILLEGIBLE TEXT
- SKEWED/SLANTED IMAGES
- COLORED PHOTOS
- BLACK OR VERY BLACK AND WHITE DARK PHOTOS
- GRAY SCALE DOCUMENTS

## IMAGES ARE BEST AVAILABLE COPY.

As rescanning documents will not correct images, please do not report the images to the Image Problem Mailbox.

### IN THE CLAIMS:

Please cancel claims 2-3, 15, 25, and 35-40, without prejudice, and amend the following claims:

1. (Currently amended) A method for plating copper metal on a substrate, comprising:

adding an anti-oxidant to providing a plating solution in an amount effective to reduce degradation of organic additives in the plating solution, comprising:

metal ions;

an acid;

halide ions;

one or more organic additives configured to enhance one or more plating characteristics; and

the <u>an at least one</u> anti-oxidant being selected from the group consisting essentially of sodium stannate, hydroquinone, butylated hydroxy toluene, and combinations thereof, wherein the anti-oxidant has a concentration between about 500 ppm and about 5000 ppm; and

contacting a substrate having an electrical bias with the plating solution to deposit a metal thereon.

- 2. (Cancelled)
- 3. (Cancelled)
- 4. (Currently Amended) The method of claim [[2]] 1, wherein the plating solution includes metal ions comprise copper ions in a concentration of between about 5 g/L and about 100 g/L.
- 5. (Currently Amended) The method of claim [[2]] 1, wherein the plating solution includes an acid [[in]] has a concentration of between about 5 g/L and about 200 g/L.



- 6. (Currently Amended) The method of claim [[2]] 1, wherein the plating solution includes halide ions comprise chloride ions in a concentration of between about 10 ppm and about 200 ppm.
- 7. (Original) The method of claim 1, wherein the amount of anti-oxidant added into the plating solution per unit time is calculated to correspond to an amount of organic additives degrading in the plating solution per unit time.
- 8. (Currently Amended) The method of claim 1, wherein the plating solution comprises:

copper ions at a concentration of between about 5 g/L and about 100 g/L; [[an]] the acid at a concentration of between about 5 g/L and about 200 g/L; chloride ions at a concentration of between about 10 ppm and about 200 ppm; sodium stannate at a concentration of between about 500 ppm and about 5000; and

at least one organic plating additive configured to enhance a plating characteristic of the metal copper plating on the substrate.

- 9. (Original) The method of claim 8, wherein the at least one organic plating additive comprises at least one of a leveler, a suppressor, and an accelerator.
- 10. (Original) The method of claim 1, further comprising: disposing of the entire plating solution after a period of time; and replacing the plating solution.
- 11. (Currently Amended) A method for plating metal on a substrate, comprising: disposing the substrate and an anode in a plating solution, the plating solution comprising:

metal ions;

an acid;

### halide ions;

one or more organic additives configured to enhance one or more plating characteristics; and

at least one anti-oxidant <u>selected from the group consisting of sodium</u> <u>stannate, hydroquinone, butylated hydroxy toluene, and combinations thereof in an amount effective to reduce degradation of the one or more organic additives having a <u>concentration between about 500 ppm and about 5000 ppm</u>; and</u>

<u>electroplating the</u> metal ions from the plating solution onto the substrate.

- 12. (Original) The method of claim 11, further comprising: disposing of the entire plating solution after a period of time; and replacing the plating solution.
- 13. (Currently Amended) The method of claim 11, wherein the metal ions comprise copper ions.
- 14. (Currently Amended) The method of claim 11, wherein the metal ions comprise copper ions in a concentration between about 5 g/L and about 100 g/L.
- 15. (Cancelled)
- 16. (Currently Amended) The method of claim 11, wherein the <u>at least one</u> antioxidant is sodium stannate at a concentration of between about 500 ppm and about 5000 ppm.
- 17. (Currently Amended) The method of claim 16, wherein the plating solution further halide ions comprise[[s]] chloride ions at a concentration of between about 10 ppm and about 200 ppm.

- 18. (Currently Amended) The method of claim 16, wherein the plating solution further comprises an acid has at a concentration of between about 5 g/L and about 500 g/L.
- 19. (Currently Amended) The method of claim 11, wherein the plating solution comprises:

copper ions at a concentration of between about 5 g/L and about 100 g/L; [[an]] the acid at a concentration of between about 5 g/L and about 200 g/L; chloride ions at a concentration of between about 10 ppm and about 200 ppm;

sodium stannate at a concentration of between about 500 ppm and about 5000 ppm.

20. (Currently Amended) A plating solution for an electrochemical plating system, comprising:

a liquid solution containing copper ions to be plated on a substrate;

an acid;

and

halide ions;

at least one organic plating additive configured to facilitate a plating characteristic of the copper ions onto [[a]] the substrate; and

at least one anti-oxidant in an amount sufficient to reduce the degradation of the at least one organic plating additive in the plating solution selected from the group consisting of sodium stannate, hydroquinone, butylated hydroxy toluene, and combinations thereof, wherein the anti-oxidant has a concentration between about 500 ppm and about 5000 ppm.

- 21. (Original) The plating solution of claim 20, wherein the liquid solution comprises copper sulfate.
- 22. (Original) The plating solution of claim 20, wherein the copper ions are at a concentration of between about 5 g/L and about 100 g/L.

- 23. (Currently Amended) The plating solution of claim 22, further comprising an wherein the acid [[at]] has a concentration of between about 5 g/L and about 200 g/L.
- 24. (Currently Amended) The plating solution of claim 22, further comprising wherein the halide ions comprise chloride ions at a concentration of between about 10 ppm and about 200 ppm.
- 25. (Cancelled)
- 26. (Original) The plating solution of claim 22, wherein the anti-oxidant is sodium stannate at a concentration of between about 500 ppm and about 5000 ppm.
- 27. (Currently Amended) The plating solution of claim 20, further comprising[[;]]:

the copper ions at a concentration of between about 5 g/L and about 100 g/L; [[an]] the acid solution at a concentration of between about 5 g/L and about 200 g/L;

chloride ions at a concentration of between about 10 ppm and about 200 ppm; and

sodium stannate at a concentration of between about 500 ppm and about 5000 ppm.

- 28. (Original) The plating solution of claim 20, wherein the at least one organic plating additive comprises at least one of a suppressor, leveler, and an accelerator.
- 29. (Original) A method for reducing degraded organic plating additives in an electrochemical plating solution, comprising adding sodium stannate to the electrochemical plating solution, the sodium stannate being added in an amount corresponding to a time varying amount of degraded organic plating additives generated in the electrochemical plating solution.

- 30. (Original) The method of claim 29, wherein a concentration of the sodium stannate is between about 500 ppm and about 5000 ppm.
- 31. (Original) The method of claim 29, wherein the electrochemical plating solution is configured to plate copper.
- 32. (Original) The method of claim 31, wherein the electrochemical plating solution includes copper ions in a concentration of between about 5 g/L and about 100 g/L.
- 33. (Original) The method of claim 31, wherein the electrochemical plating solution includes an acid in a concentration of between about 5 g/L and about 200 g/L.
- 34. (Original) The method of claim 31, wherein the plating solution includes chloride ions in a concentration of between about 10 ppm and about 200 ppm.

35-40. (Cancelled)